

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Tetsuo SHIMOMURA et al.  
App. No : 10/598,717  
Filed : September 8, 2006  
For : POLISHING PAD AND  
SEMICONDUCTOR DEVICE  
MANUFACTURING METHOD  
Examiner : Alvin J Grant  
Art Unit : 3723  
Conf # : 9262

CERTIFICATE OF EFS WEB  
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July 11, 2008

(Date)

  
Curtiss C. Dosier, Reg. No. 46,670AMENDMENT**Mail Stop Amendment**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed April 11<sup>th</sup>, 2008, please reconsider the present application in light of the following amendments and comments.

**Amendments to the Specification** begin on page 2 of this paper.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 3 of this paper.

**Remarks/Arguments** begin on page 9 of this paper.